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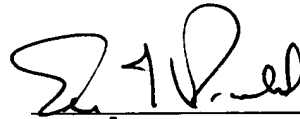
REMARKS

Attached is a marked-up version of the changes being made by the current amendment.

Applicants ask that all claims be examined Please apply any other charges or credits to
Deposit Account No. 06-1050.

Respectfully submitted,

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Version with markings to show changes made

In the claims:

Claims 1-21 have been cancelled.

Claims 22 and 24-37 have been amended as follows:

22. (Once Amended) A method of producing an electroformed shaving cutter [in which]
comprising:

a) providing a substrate that in an at-rest position has a substantially three-dimensional electrically conductive surface:

b) applying a coating of electrophoretic photoresist [is applied] to the [a substrate having an] electrically conductive surface by passing an electrical current therethrough[, the surface having non-zero Gaussian curvature];

[b]c) exposing the photoresist [is exposed] to a suitable source of electromagnetic radiation through a mask whose shape conforms closely to that of the substrate;

[c]d) developing the photoresist [is developed]; and

[d]e) electrodepositing a metallic layer [is electrodeposited] onto [the] conductive surface regions of the substrate not coated with the photoresist.

25. (Once Amended) A method according to [any one of] claim[s] 22 [to 24 in which]
further comprising providing the mask [is provided] with a plurality of non-elongate apertures.

26. (Once Amended) A method according to claim 25 wherein [the] each of the plurality of [the] apertures [each have] has a diameter in the range 600 to 800 microns.

27. (Once Amended) A method according to [any one of] claim[s] 22 [to 26], further comprising providing [wherein] the mask [is provided] with a plurality of elongate apertures.

28. (Once Amended) A method according to claim 27 wherein [the] each of the plurality of apertures [have] has a length of 400 to 2200 μm and a width of 400 to 800 μm .

29. (Once Amended) A method according to [any one of] claim[s] 22 [to 28 in which] wherein the metallic layer has a varying relief pattern.

30. (Once Amended) A method according to [any one of] claim[s] 22 [to 29], wherein [in which] the mask is made of ductile metal[, e.g. copper].

31. (Once Amended) A method according to [any one of] claim[s] 22 [to 30 in which] further comprising separating the metallic layer [is separated] from the substrate by at least one of peeling [or by] and dissolution of the substrate.

32. (Once Amended) A method of manufacturing a three-dimensional electroforming mask [for use in the method of any one of claims 22 to 31] comprising [the step of]:
providing a mandrel defining a three-dimensional surface; and
forming an electrically conductive surface pattern on the three-dimensional surface, said forming comprising [by] etching using a laser.

33. (Once Amended) A method according to claim 32 [in which] wherein the forming of the electrically conductive surface pattern further comprises [is produced by] coating an electrically conductive substrate with photoresist and selectively removing portions of the photoresist using the laser.

34. (Once Amended) A method according to claim 32 [in which] wherein the forming of the electrically conductive surface pattern further comprises [is produced by] coating an electrically insulating substrate with a conductive layer, and selectively removing portions of the conductive layer using the laser.

35. (Once Amended) A method according to claim 34 [wherein the coating is applied by] further comprising electroforming the conductive layer to a desired thickness.

36. (Once Amended) A method according to claim [34 or] 35 [in which] wherein the etching step is followed by [a thickening step using] electroforming of the conductive layer to [a] the desired thickness.

37. (Once Amended) A method according to claim 34, [35 or 36 in which] further comprising removing the coating [is removed] from the substrate.

Please add the following new claims:

38. (New) A method according to claim 22, wherein the surface has a non-zero Gaussian curvature.

39. (New) A method according to claim 22, wherein the mask is made of copper.

40. (New) A method according to claim 34 wherein the coating of electrophoretic photoresist has a substantially uniform thickness.